

**Maulana Abul Kalam Azad University of Technology, West Bengal***(Formerly West Bengal University of Technology)***Syllabus for B. Tech in Electronics & Communication Engineering**

(Applicable from the academic session 2018-2019)

<b>PE-EC603A</b>	<b>Introduction to MEMS</b>	<b>3L:0T:0P</b>	<b>3 credits</b>
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Introduction and Historical Background,

Scaling Effects.

Micro/Nano Sensors, Actuators and Systems overview: Case studies. Review of Basic MEMS fabrication modules: Oxidation, Deposition Techniques, Lithography (LIGA), and Etching. Micromachining: Surface Micromachining, sacrificial layer processes, Stiction;

Bulk Micromachining, Isotropic Etching and Anisotropic Etching, Wafer Bonding. Mechanics of solids in MEMS/NEMS: Stresses, Strain, Hooke's law, Poisson effect, Linear Thermal Expansion, Bending; Energy methods, Overview of Finite Element Method, Modeling of Coupled Electromechanical Systems.

**Text/Reference Book:**

1. G. K. Ananthasuresh, K. J. Vinoy, S. Gopalkrishnan K. N. Bhat, V. K. Aatre, Micro and Smart Systems, Wiley India, 2012.
2. S. E. Lyshevski, Nano-and Micro-Electromechanical systems: Fundamentals of Nano-and Microengineering (Vol. 8). CRC press, (2005).
3. S. D. Senturia, Microsystem Design, Kluwer Academic Publishers, 2001.
4. M. Madou, Fundamentals of Microfabrication, CRC Press, 1997.
5. G. Kovacs, Micromachined Transducers Sourcebook, McGraw-Hill, Boston, 1998.
6. M.H. Bao, Micromechanical Transducers: Pressure sensors, accelerometers, and Gyroscopes, Elsevier, New York, 2000.

**Course Outcomes:**

At the end of the course the students will be able to

1. Appreciate the underlying working principles of MEMS and NEMS devices.
2. Design and model MEM devices.